# **LSM 800 Basic Operation**



MultiChannel & TimeSeries & Z-Stack & TileScan



Lu Xi

# **Agenda**



- 1 Startup and Shutdown of the System
- 2 Acquiring Multi-Channel images
- 3 Z-stack image
- 4 Time Series image
- 5 Tile Scan
- 6 Airyscan Imaging

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Startup of the System





## 打开稳压电源:

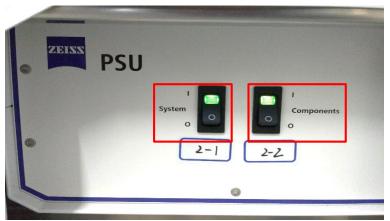
- a、打开稳压电源背后总开关;
- b、打开稳压电源前面开关;
- c、确定稳压电源显示220V;



Startup of the System



开启总电源后,按照如下顺序开启各部件电源: 1、打开"System"和"Components";

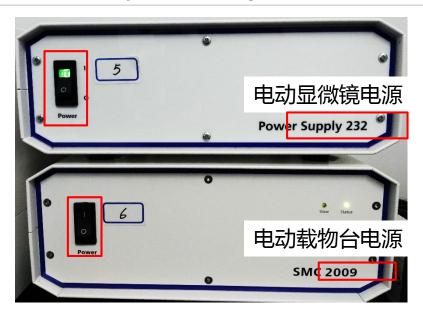


2、将Laser Module "LM" 的钥匙从 "0" 转到 "1"





Startup of the System



- 3、打开电动显微镜电源 "Power Supply
- 232"和电动载物台电源"SMC 2009";
  - (如果是手动载物台没有 "SMC 2009")
- 4、打开金属卤化物灯"HXP 120"(注意
- :30分钟之内不要反复开关!!)





## Startup of the System



- 3、打开电动显微镜电源 "Power Supply
- 232"和电动载物台电源"SMC 2009";
- (如果是手动载物台没有 "SMC 2009")
- 4、打开金属卤化物灯X-Cite
- (注意:30分钟之内不要反复开关!!)





Startup of the System



\*注意:如果同时配置有Definite Focus 2,开机时需要在开启显微镜电源( Power Supply 232) 之前打开Definite

\*Focus Controller.2 电源开关在背后





Startup of the System



5、启动ZEN软件(Blue),选择 "ZEN system";

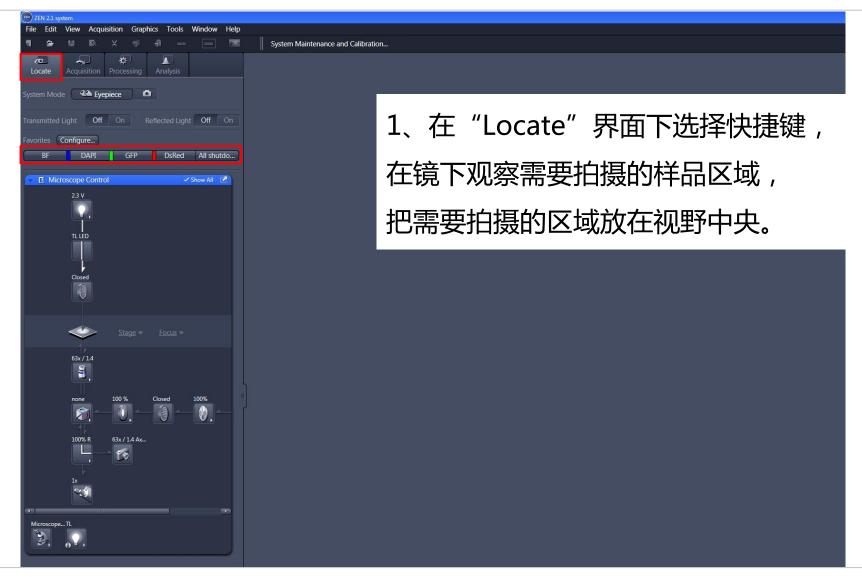


# **Agenda**



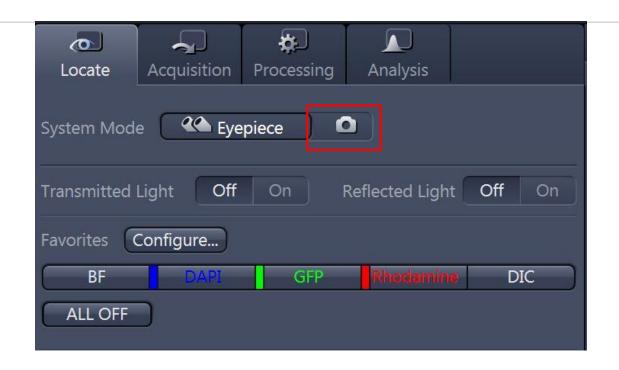
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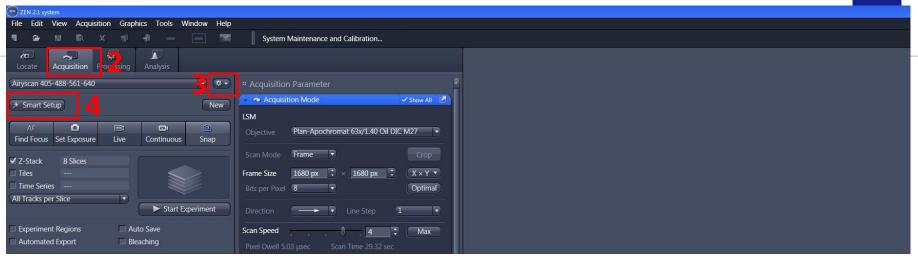
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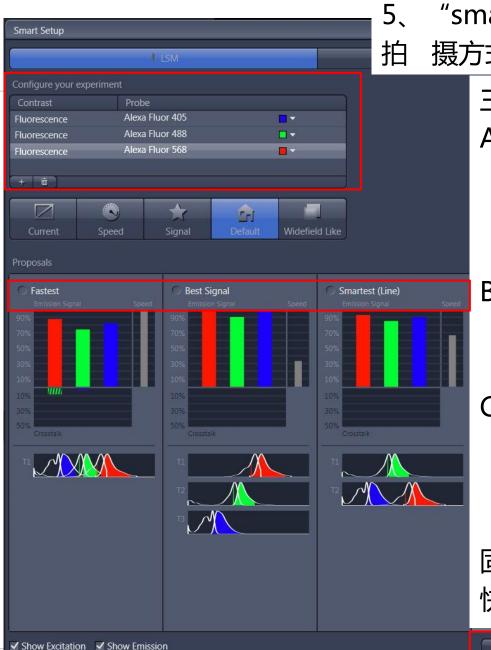
\*如果配置中带有CCD,在"Locate"界面,可以选择相机图标,用CCD进行单张明场或荧光成像。





- 2、进入 "Acquisition" 界面;
- 3、选择之前保存好的光路设置 > "channel" 和 "Acquisition mode" 设置
- 4、或者新建光路设置→ "Smart Setup"





5、"smart setup"中选择染料名称,并选择 拍 摄方式后,"OK"

## 三种拍摄方式:

A、Fastest 拍摄速度最快, 发射波长接近的荧光染料间存在串 色现象;

- B、Best signal 拍摄速度最慢; 基本避免了发射荧光的串色;
- C、Smartest (Line) 结合上述两者优势,减少串色 的同时拍摄速度较快,但是光路中 硬件设置不能改变。

固定样本推荐使用Best signal、变化较 快的样本推荐使用Smartest或者Faster

## **Channels**



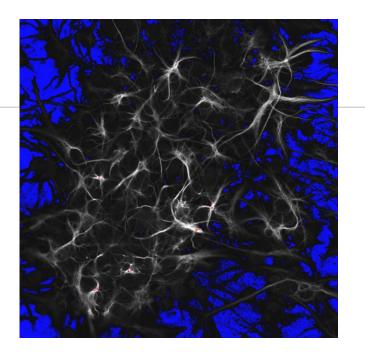
6、在 "live" 下设置Channels中的激光强 度 "Laser" , 针孔大小 "Pinhole" 器 "Gain"值,以及 "digital gain"或 "digital offset";每个track单独设置, 选中该track(选中track高亮); A、"Pinhole"一般设置为1 AU,增大

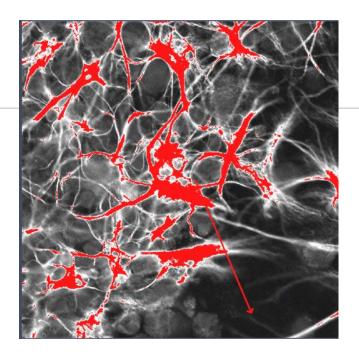
Pinhole可以提高图像亮度,但会增加非焦 面信息;减少Pinhole可以增加景深,但是 会减少图像亮度;

B、"Gain"和"Digital Gain"增加可以 增加图像亮度,但是也会提高背景噪音。

"High Intensity Laser Ranger" : 不勾选最小激光值能达到0.01%,但最高值 分别只能达到3.5%(405),4.5%(488) 和5% (561、640) 勾选后激光值能达到100%,但最小值不能

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16



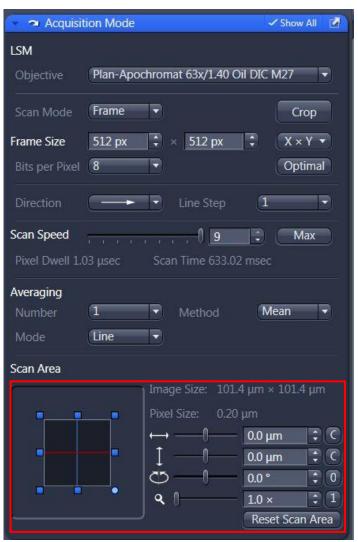
设置原则保证图像不要过曝,尽量 减少背景噪音:

在live下选择"range indicator"可以显示出曝光程度;

## **Acquisition Mode**



17



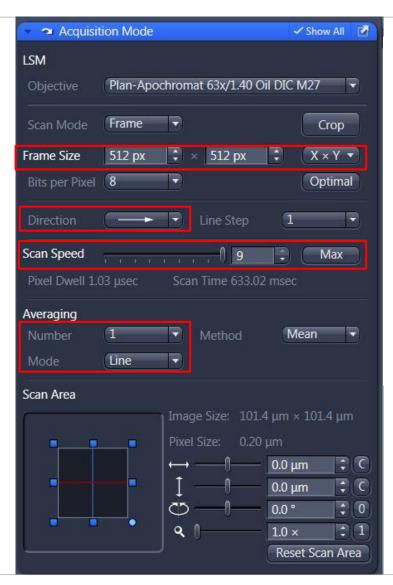
- 7、在Acquisition Mode下主要设置如下参数:
- A、通过scan area选择扫描区域或通过图像窗
- 口下的 "crop" 选择扫描区域;



## **Acquisition Mode**



18



- B、设置Scan Speed:扫描速度越慢,信噪比越好,但光漂白越多;
- C、Averaging:增加averaging次数可以减少噪音,但会增加扫描时间;
- D、Direction:双向扫描可以减少扫描时间;
- E、Frame Size:一般选择512×512或

1024×1024,图像越大,扫描时间越长

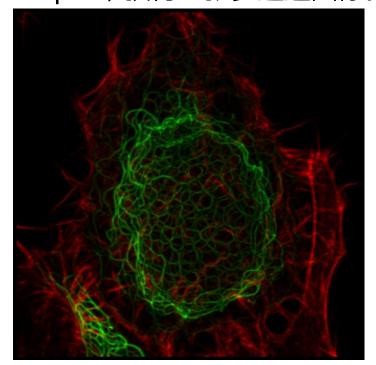


19





8、选择需要成像的track,单击 "Snap";获得一张多通道图像。



## **Experiment Manager and Reuse**



20



可以通过Experiment Manager来保存拍摄的参数,或打开已经保存的图片(czi格式),通过"Reuse"来调用上次拍摄的参数设置



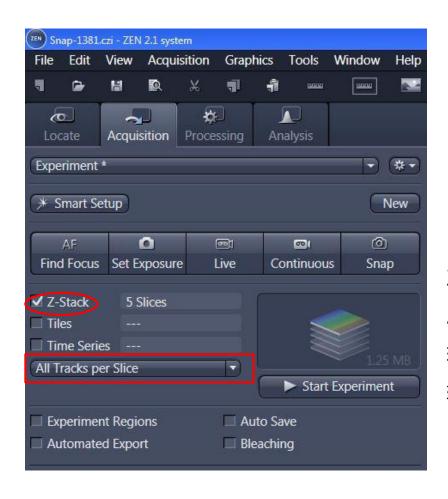
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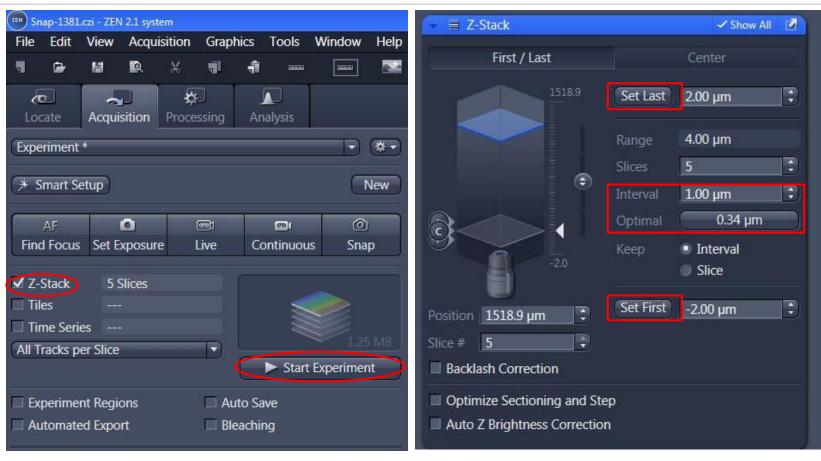
Z-stack层扫在多通道荧光下有两种模式:

A、Full Z-stack per slice,单个荧光通道下进行z 轴层扫后切换到另一个荧光通道继续z轴层扫(这种Z 轴扫描方式速度较快);

B、All Tracks per Slice,每层进行多荧光扫描;

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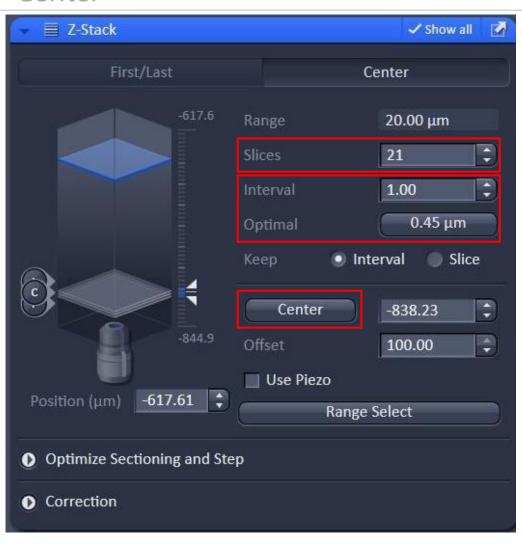
## First/Last



- 1、选择Z-stack;
- 2、在live下调节焦距选择层扫图像的上下范围: "set first" 和 "set last" ;
- 3、单击 "optimal" 让间距在最适合范围;
- 4、单击 "Start Experiment"



#### Center

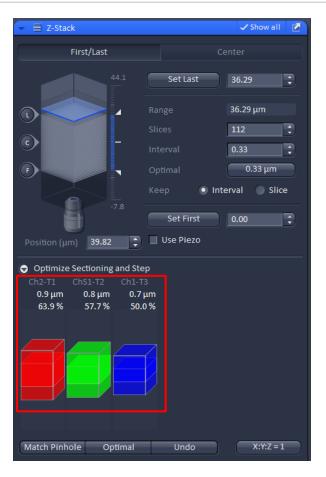


1、center模式下, live下选择成像的中间位置, 单击 "center", 然后设置需要层扫的层数Slices, 并单击"optimal";

2、单击 "Start Experiment"



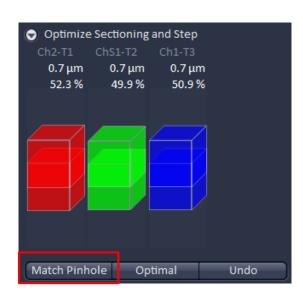
#### Match Pinhole



多通道荧光拍摄Z-stack需要考虑 光切厚度不一致的问题:

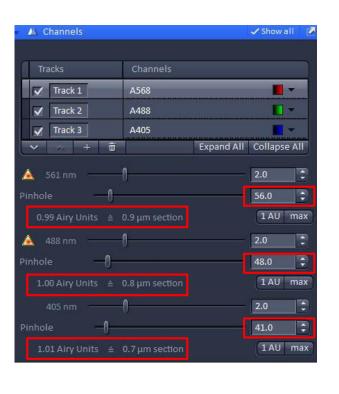
1、可以通过点击"Match Pinhole"自动调节不同track的 针孔使光切厚度相似;

\*这种方法的缺点在于可能会使长 波长的针孔过于小,不利于弱荧 光成像。

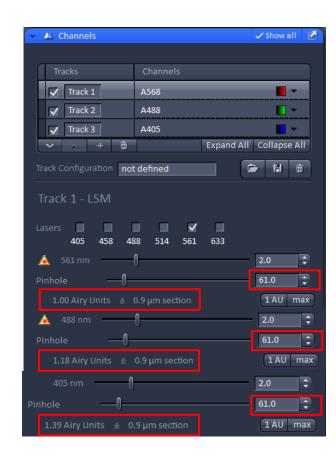


# ZEIZZ

#### Match Pinhole



2、通过手动调节针孔到一致,可以保证荧光强度的同时,保证光切厚度一致。



# **Agenda**

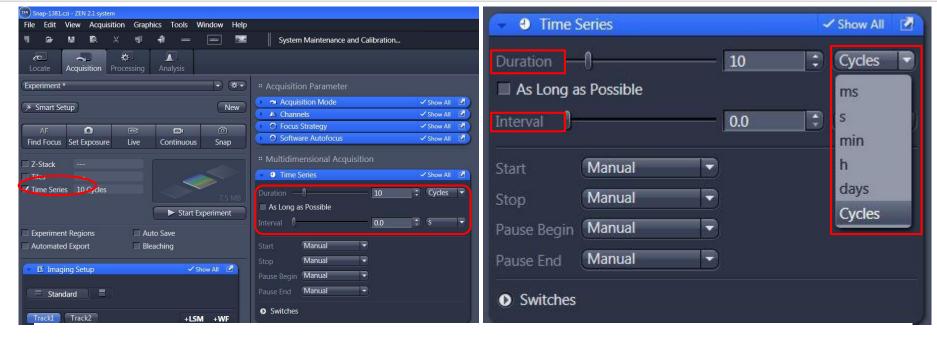


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## **Time Series image**





- 1、选择 "Time Series"
- 2、拍摄要持续的时间,如循环数cycles或者其他具体时间;
- 3、循环之间的间隔Interval; interval:两次循环开始时间的间隔,因此interval包含了上一个循环的拍摄时间;
- 4、 "Start Experiment"

# **Agenda**

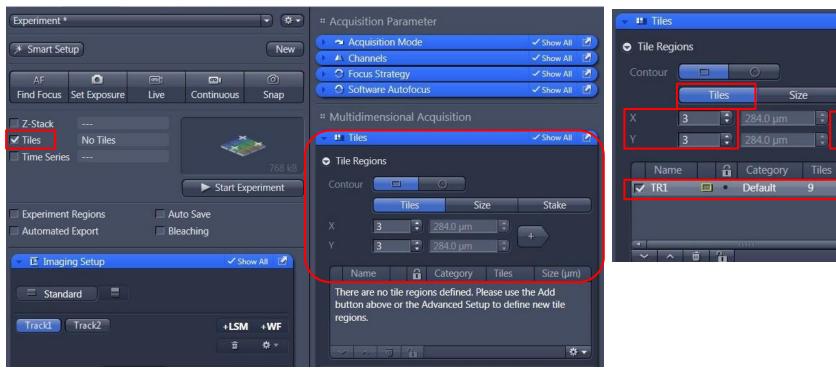


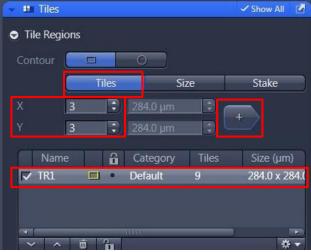
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## Tiles

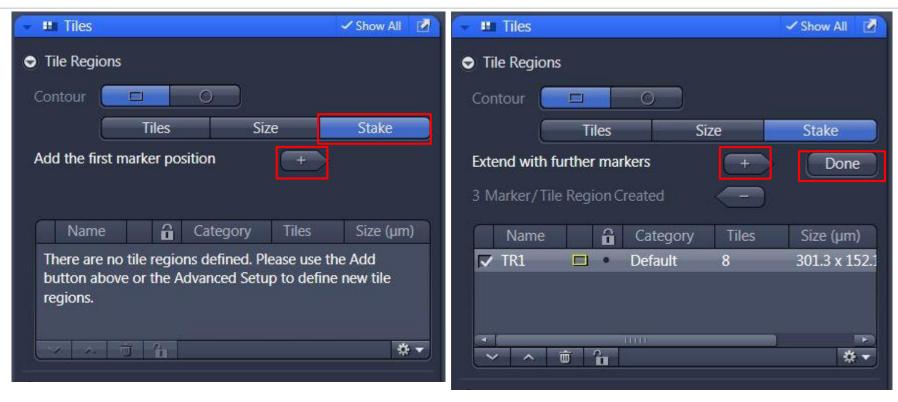




- 在 "Tiles" 模块下 "Tiles" 方法代表以现在视野为中心拍摄拼图,
- 选择 "Tiles" 下的 "Tiles" 方法;
- "X" & "Y" 分别代表水平和垂直方向拼图范围;
- 点击"+",将要拼图的范围添加到拼图区域中;
- "Start Experiment"



#### Stake

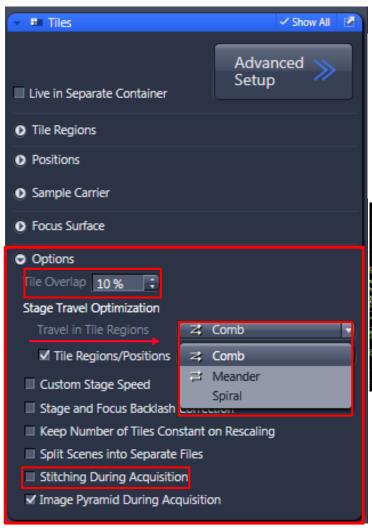


"Stake" 方法能够通过定义拼图边缘自动计算拼图大小,完成拼图:

- 1、"Stake"下通过移动载物台到想拼接的样品边缘,单击"+",添加边缘范围。所有边缘定义
- 后,点击 "Done",软件自动定义拼图范围。
- 2、 "Start Experiment" 。

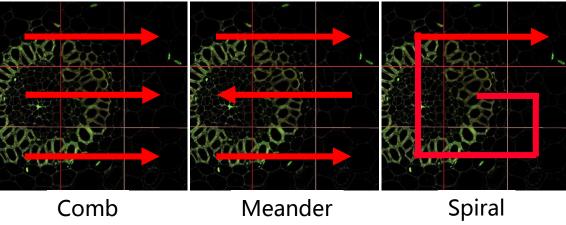


## Option



"Option"中几个关键参数:

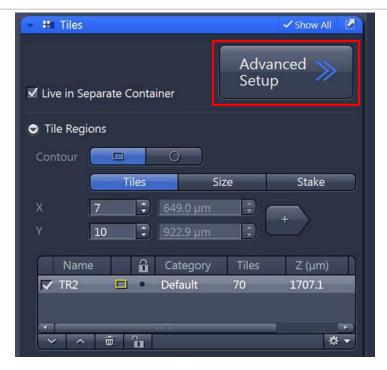
- 1、"Tile Overlap"代表图片边缘互相重叠百分比,一般默认10%;
- 2、 "Travel in Tile Regions" 代表拼图时的方向:
  - "Comb":单方向拼图;"Meander":双向拼图;
  - "Spiral" :螺旋形从中向外拼图。



3、 "Stitching During Acquisition" 在拼图后自动拼接,消除拼图中的接缝。



## Advanced Setup



#### 高级拼图功能主要包括两个部分:

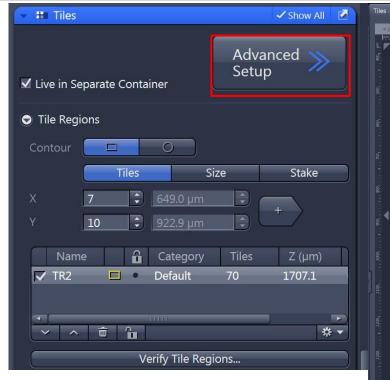
1、可以通过拼图前分析拼图区域的焦距变化,有利于校正拼图不同焦距的问题(support point);

2、如果同时配置有CCD,可以通过CCD的快速成像来获取预扫图像,辅助拼图区域的选择(preview scan)

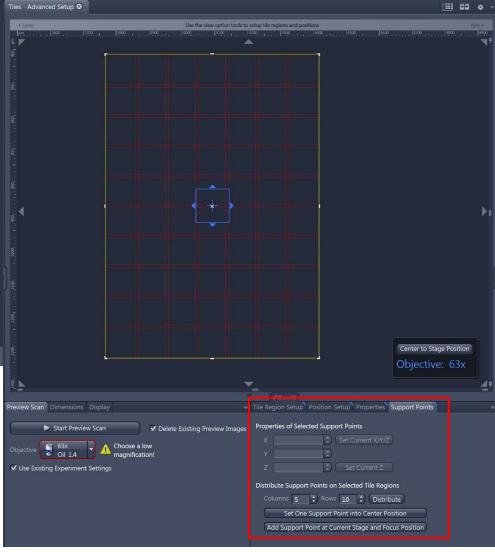


34

#### **Focus Surface**



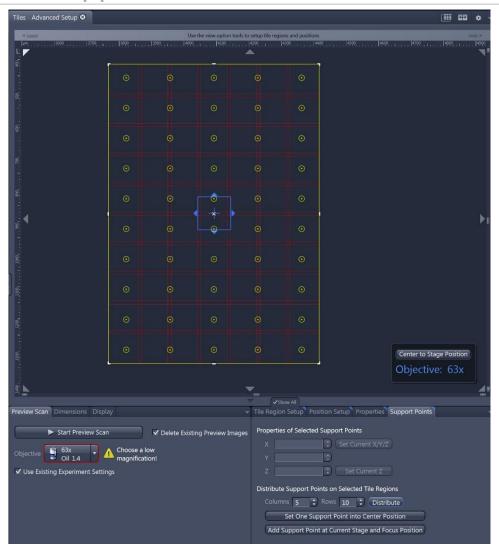
1、建立好拼图范围后选择"Advanced Setup",在右侧看见扫描区域,并进入下方选项"Support Points"

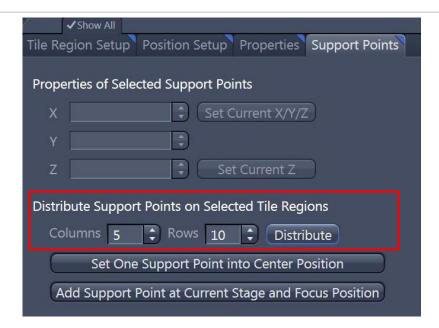




35

## Support Point

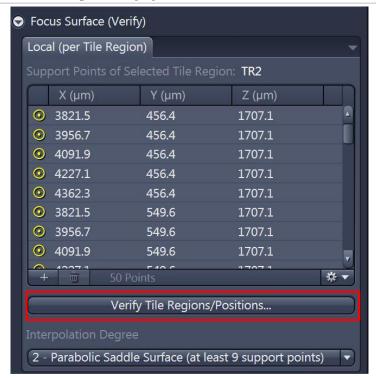




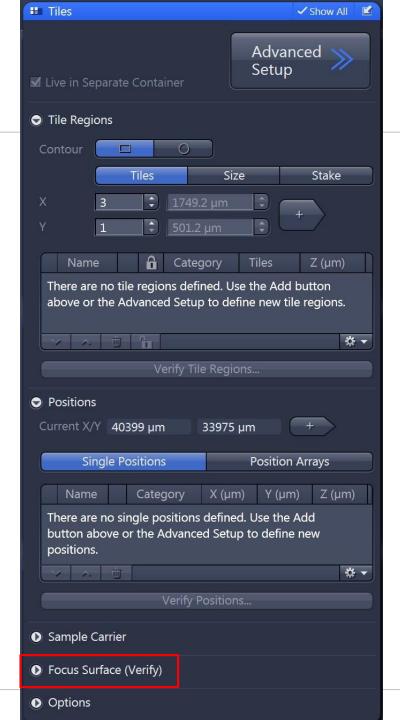
2、在"Support Points"选项下选择支持点,这些支持点将帮助你确定拼图区域内的焦距变化;

设定好需要分布的支持点的行列数量后点击 "Distribute" ,拼图区域上出现黄色小圆点,代表支持点,可以手动调节这些点的具体位置。

## Verify Support Points



3、在 "Tiles" 窗口下选择 "Focus Surface (verify)" , 点击 "Verify Tile Regions/Positions" 对选好的support points进行校正;







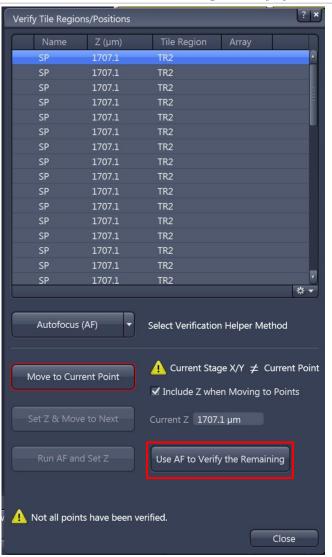
### Verify Support Points



- 4、根据配置不同,主要包括以下三种校正方法:
- a. None ( Manual adjustment ) 手动校正,在 预览模式 "Live"下,双击第一个SP ( Support Point ) 进行手动调焦后保存焦距位置 "Set Z & Move to Next ",随后对后续SP 进行逐个校正;
- b. Autofucus (AF) 软件自动对焦,通过软件计算的方法找到最佳焦距;
- c. Definite Focus (DF)自动对焦系统,需要硬件Definite Focus支持,通过DF能够迅速找到介质表面来确定样品焦面。



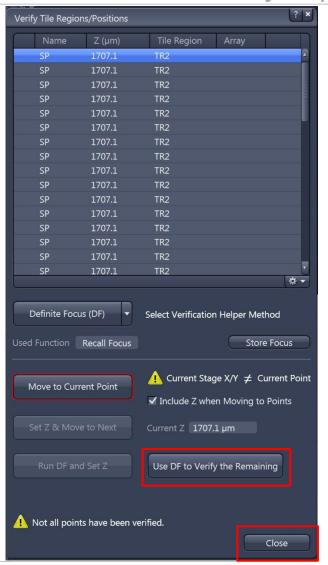
# **Autofocus Verify Support Points**

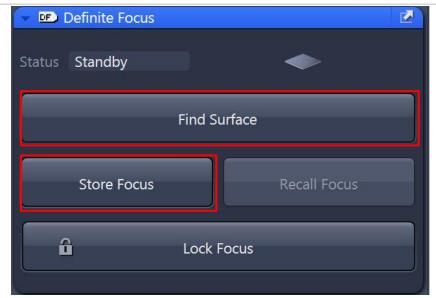


5、选择AF校正方法后选择"Use AF to Verify the Remaining",软件会自动对所有Support Points进行焦距校正;



### **Definite Focus Verify Support Points**

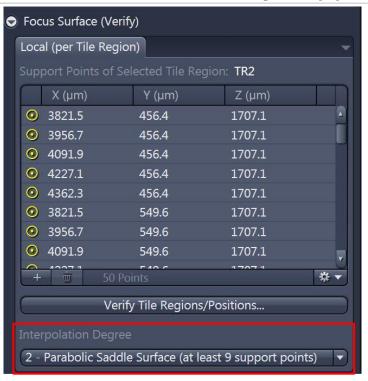




- 6、选择DF校正方法后,
- a. 先在软件右侧Definite Focus工具栏中选择 "Find Surface"找到样品介质面,随后手动调节焦距到感兴趣 的焦面,选择"Store Focus";
- b. 最后在Verify界面选择 "Use DF to Verify the Remaining" ,软件会自动对所有Support Points进行焦距校正。



### Definite Focus Verify Support Points

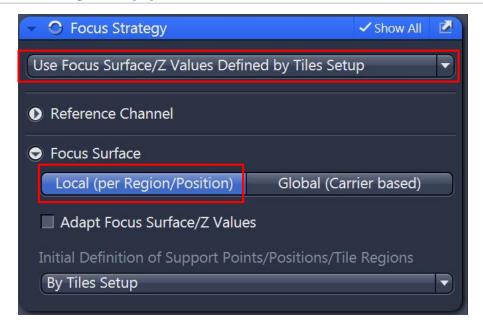


7、校正所有SP后,选择适合的"Interpolation Degree";样品表面越不平整需要Interpolation Degree越高,选择的SP数量超过Interpolation Degree需要的最小值可以增加计算的可靠程度。



41

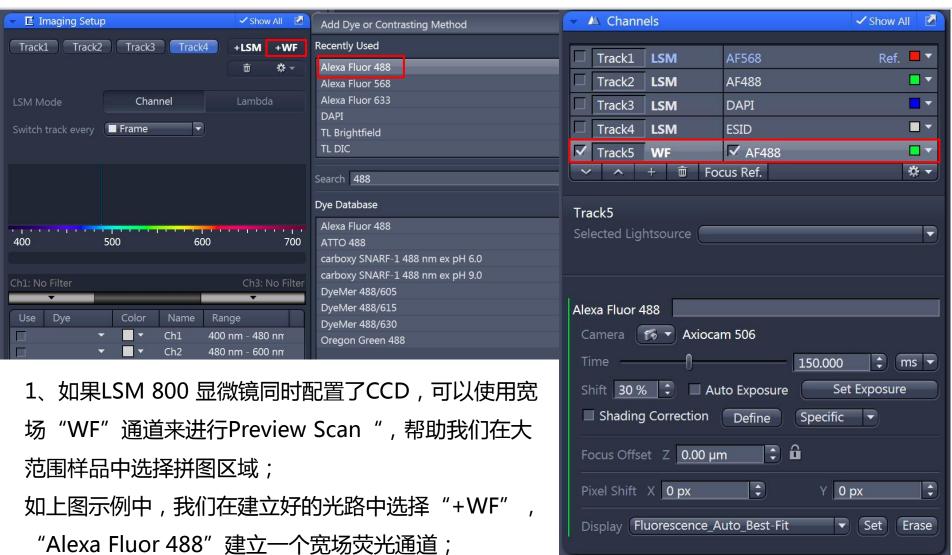
### Definite Focus Verify Support Points



- 8、随后在 "Focus Strategy" 工具栏中确定如上图所示选项:对焦方法为 "Use Focus Surface/Z Values Defined by Tiles Setup", Focus Surface的方法为 "Local (per Region/Position);
- 9、上述设置结束后,点击 "Start Experiment" 拼图



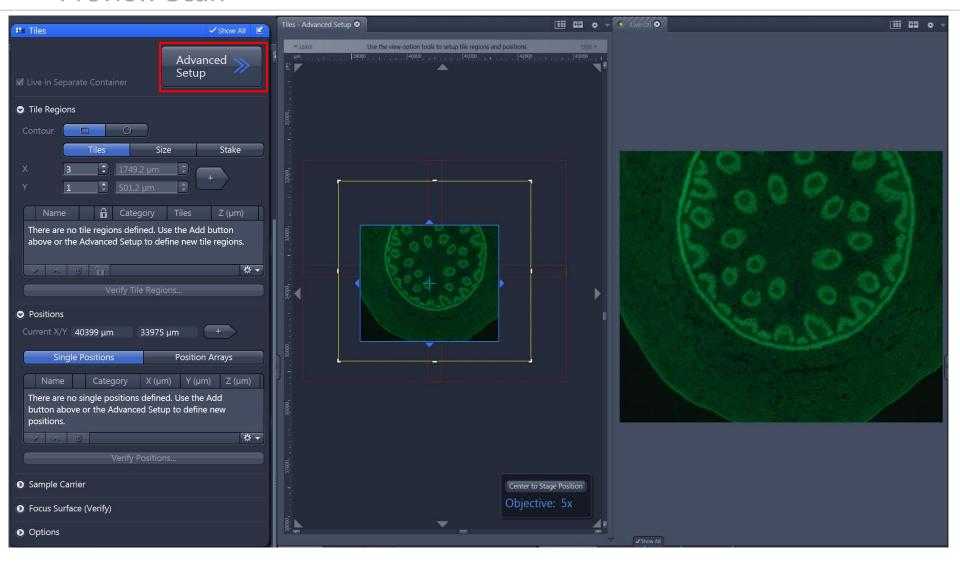
Preview Scan



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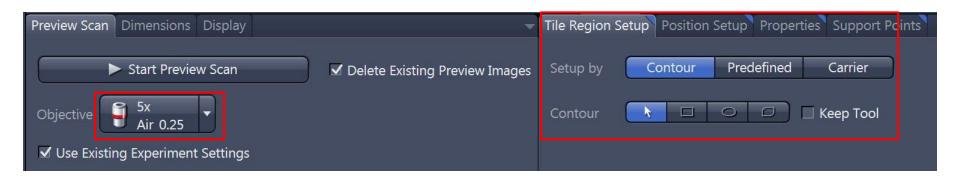
#### Preview Scan



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#### Preview Scan



- 2、勾选 "Tiles" 并进入 "Advanced Setup" ; 一般会选择最小放大倍数物镜来进行Preview Scan , 如5X ;
- 3、通过 "Tile Region Setup" 定义预扫描的区域,如通过Contour直接手动绘制扫描范围(上页图中黄色实线框);
- 4、点击 "Start Preview Scan" 进行预扫描;



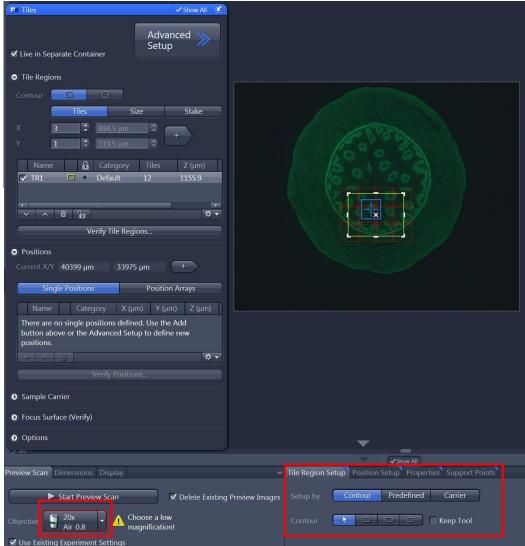
45

#### Preview Scan



5、得到Preview Scan的预扫描图后,勾选共聚焦"LSM"通道,同时可以更换更高倍的物镜,如20X,然后通过"Tile Region Setup"工具栏直接在预扫描图上重新选择拼图范围。

\*注意:预扫结束后要删除之前预扫描时设定的扫描范围后再设置新的扫描范围!6、随后点击"Start Experiment"对新选定的扫描区域进行拼图。

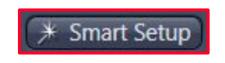


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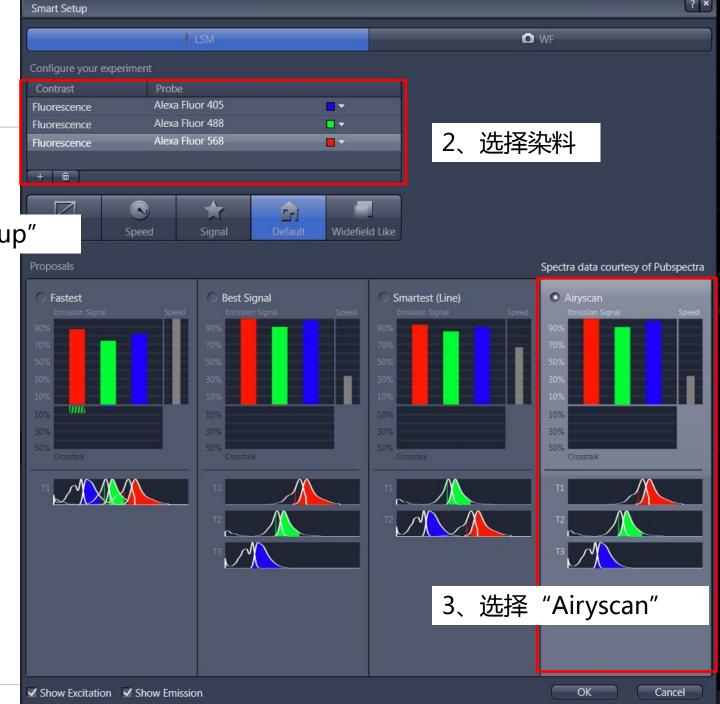


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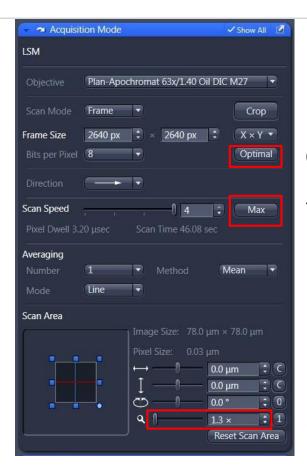
1、进入 "Smart Setup"







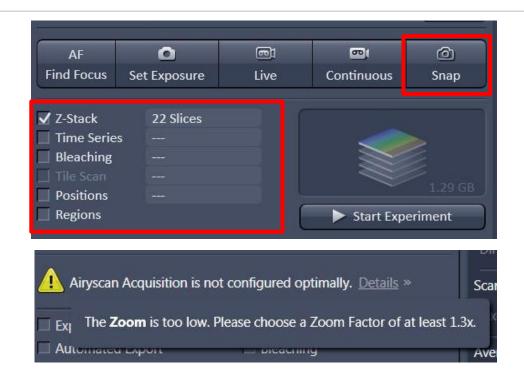
4、设置激光大小"Laser",检测器"Master Gain"和 "Digital Gain"



- 6、 "Frame Size" 选择 "Opti
- 7、"Scan Speed"选择"Max'

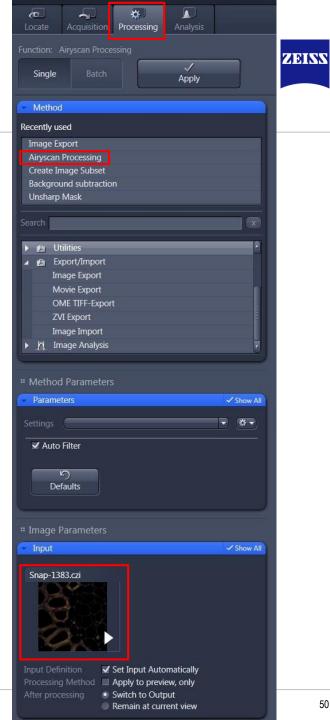
5、zoom值的大小不能小于1.3



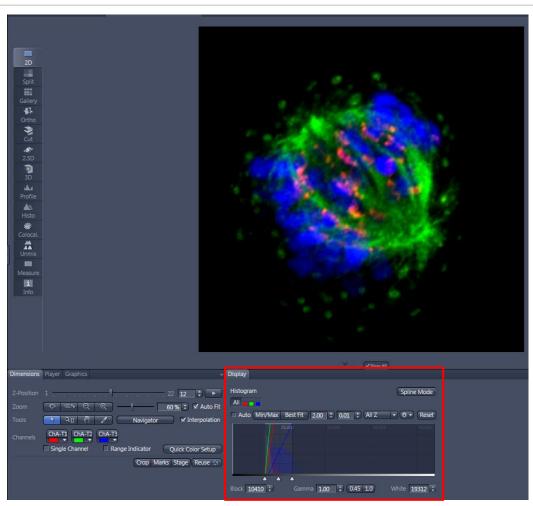


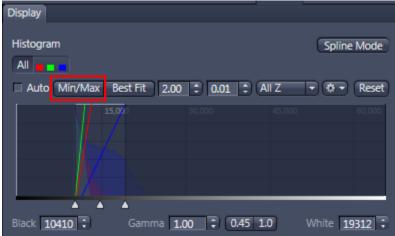
8、如果有参数设置不能满足达到Airyscan 最高分辨率,软件会有相应提示,根据提示更改参数后可以进行二维图像拍摄(Snap)或者多维图像拍摄

9、按照 "Processing → Airyscan Processing → Input → Apply"进行图像处理。如果是z-stack图 像,请选择"3D"









10、处理后的图像,在Display处选择Min/Max或者手动调节显示效果

